

SRC/NSF/A*STAR Forum on 2020 Semiconductor Memory Strategies: Processes, Devices, and Architectures, Oct. 20-21, 2009, Singapore

Panel II: Prospective Materials for Memory Applications

Materials for ReRAM

Hiro AKINAGA and Hisashi SHIMA

AIST, Japan



1

SRC/NSF/A*STAR Forum on 2020 Semiconductor Memory Strategies: Processes, Devices, and Architectures, Hiro AKINAGA and Hisashi SHIMA, Oct. 20-21, 2009, Singapore



Revised by Akinaga, AIST, ver.4.0, (originally proposed by NEC)



Q: Current status and metrics of ReRAM technology

- □, CMOS compatibility (materials, process...)
- □, No physical scaling limit (in principle) strong competitiveness in price / recording-bit
- □, Ultra-fast operation, ~ 10 [ns]
- \Box , Large ON / OFF ratio, ~ 10³
- □, (tolerably) low-power operation, ~ 0.1 [mA]
- \Box , (tolerably) high endurance, ~ 10^{6~9} R/W
- \Box , (tolerably) good retention, ~ 150 °C



Background

New engineered materials play a critical role in the development of future memories. One of the important goals of materials research for memory technologies is a clear identification of the physical mechanism of memory operation. Next, an optimized materials system has to be synthesized, including e.g. precise control of composition, doping, defects etc. For a given memory technology, it is essential to optimize a 'base' materials system. For example, resistance switching effects have been reported for many families of materials, and it is highly desirable to identify one or two optimal materials for practical implementations. Reproducibility of results is serious problem with some emerging research materials. Also, stability of a material system with respect to endurance of the memory device is an important issue. Details of sample preparation, electrode

materials, interfacial properties need to be thoroughly analyzed for addressing the endurance and reproducibility challenges.

For practical applications, synthesis of materials systems with optimized operational parameters should be achieved by taking into account the costs, which may also influence materials selection. For example organic/polymer materials are potential candidates for future memories, as they may offer lower-cost integration solutions.



Background

New engineered materials play a critical role in the development of future memories. One of the important goals of materials research for memory technologies is a clear identification of the physical mechanism of memory operation. Next, an optimized materials system has to be synthesized, including e.g. precise control of composition, doping, defects etc. For a given memory technology, it is essential to optimize a 'base' materials system. For example, resistance switching effects have been reported for many families of materials, and it is highly desirable to identify one or two optimal materials for practical implementations. Reproducibility of results is serious problem with some emerging research materials. Also, stability of a material system with respect to endurance of the memory device is an important issue. Details of sample preparation, electrode materials, interfacial properties need to be thoroughly analyzed for addressing the endurance and reproducibility challenges.

For practical applications, synthesis of materials systems with optimized operational parameters should be achieved by taking into account the costs, which may also influence materials selection. For example organic/polymer materials are potential candidates for future memories, as they may offer lower-cost integration solutions.



Correction of misapprehension about the operation mechanism of binary-metal-oxide ReRAM

Filament model (Fuse-Antifuse operation)

vs (conflicting)

Interface model (incl. Schottky Barrier height modulation)



Correction of misapprehension about the operation mechanism of binary-metal-oxide ReRAM





SRC/NSF/A*STAR Forum on 2020 Semiconductor Memory Strategies: Processes, Devices, and Architectures, AIST Hiro AKINAGA and Hisashi SHIMA, Oct. 20-21, 2009, Singapore

Operation mechanism of ReRAM



NATIONAL INSTITUTE OF ADVANCED INDUSTRIAL SCIENCE AND TECHNOLOGY (AIST)

BAIST SRC/NSF/A*STAR Forum on 2020 Semiconductor Memory Strategies: Processes, Devices, and Architectures, Hiro AKINAGA and Hisashi SHIMA, Oct. 20-21, 2009, Singapore

Operation mechanism of ReRAM (sub 20nm-node)



In the nano-meter ReRAM device, the filament model does NOT conflict with the interface model. The electrochemical reaction at the interface brings about the non-volatile resistance switching.



BAIST SRC/NSF/A*STAR Forum on 2020 Semiconductor Memory Strategies: Processes, Devices, and Architectures, Hiro AKINAGA and Hisashi SHIMA, Oct. 20-21, 2009, Singapore

Operation mechanism of ReRAM (sub 20nm-node)



Key issues: To select proper combination of the electrode and the oxide layer Ellingham diagram (Gibbs Free Energy diagram) gives us the guiding principle. We can control the active cell size at will in the operation.



Q: Current status and metrics of ReRAM technology

- □, CMOS compatibility (materials, process...)
 □, No physical scaling limit (in principle) strong competitiveness in price / recording-bit
- \Box , Ultra-fast operation, ~ 10 [ns]
- \Box , Large ON / OFF ratio, ~ 10³
- \Box , (tolerably) low-power operation, ~ 0.1 [mA]
- \Box , (tolerably) high endurance, ~ 10^{6~9} R/W
- \Box , (tolerably) good retention, ~ 150 °C



Demonstration of Fast & Low-power operation

achieved by selecting the combination of Ta and CoO to fabricate the electrochemically active interface.



Fig. 4 Applied pulse voltage and writing current waveforms of **Ta/CoO/**Pt for (a) Set and (b) Reset. Set and reset conditions are 2.2 V 50 ns and -1.4 V 50 ns, respectively.

2008 International Conference on Solid State Devices and Materials (**SSDM 2008**). Date : September 23-26, 2008



AIST

Operation mechanism of ReRAM



Key issues: To select proper combination of the electrode and the oxide layer We can control the active cell size at will in the operation.



Background

New engineered materials play a critical role in the development of future memories. One of the important goals of materials research for memory technologies is a clear identification of the physical mechanism of memory operation. Next, an optimized materials system has to be synthesized, including e.g. precise control of composition, doping, defects etc. For a given memory technology, it is essential to optimize a 'base' materials system. For example, resistance switching effects have been reported for many families of materials, and it is highly desirable to identify one or two optimal materials for practical implementations.

Reproducibility of results is serious problem with some emerging research materials. Also, **stability** of a material system with respect to endurance of the memory device is an important issue. Details of sample preparation, electrode materials, interfacial properties need to be thoroughly analyzed for addressing the endurance and reproducibility challenges.

For practical applications, synthesis of materials systems with optimized operational parameters should be achieved by taking into account the costs, which may also influence materials selection. For example organic/polymer materials are potential candidates for future memories, as they may offer lower-cost integration solutions.



What are the key materials challenges (the critical material properties) for ReRAM technologies?

STEP1:

To synthesize the highly-reproducible oxide interface

STEP2:

To decrease the operation current for higher endurance

STEP3: To realize zero-current resistance switch (Namely, ReRAM operated by Voltage)

These material challenges will open up the new and wider application area of ReRAM!





*SRC/NSF/A*STAR Forum on 2020 Semiconductor Memory Strategies: Processes, Devices, and Architectures, Hiro AKINAGA and Hisashi SHIMA, Oct. 20-21, 2009, Singapore*

Thank you very much!

ご清聴ありがとうございました。

